

207.9 - Microscale Dimensional Measurement Standards

SRM 2800 is intended primarily for use in calibrating the magnification or scale of microscopes used to make dimensional measurements. These microscopes include optical and scanning electron microscopes, imaging in either transmission or reflection modes, and scanning probe microscopes.

SRM 5000 is intended primarily for calibrating optical microscopes used to make overlay measurements. It is also useful in calibrating other types of instruments capable of making overlay measurements, such as scanning electron microscopes or atomic force microscopes, provided that they have an appropriate level of magnification and have the proper sample-holding capabilities.

SRM 5001 is intended primarily for calibrating high accuracy two dimensional (X-Y) Photomask/Reticle registration metrology tools. In particular, this calibration artifact can also be used in the metrology tools capable of holding any artifact with these dimensions in need of a calibrated measurement field. An example of additional tools are defect inspection and classification tools, optical tools used in manufacture of flat panel displays or scanning electron microscopy tools used in photomask and wafer inspection.

PLEASE NOTE: The tables are presented to facilitate comparisons among a family of materials to help customers select the best SRM for their needs. For specific values and uncertainties, the certificate is the only official source.

SRM	Description	Unit Size
2800	Microscope Magnification Standard	each
5000	Overlay Wafer Standard	each
5001	Two-Dimensional Grid Photomask, Std	each
8820	Scanning Electron Microscope Scale Calibration Artifact	1 chip